

# Thermoelectric Property of Silicon Nanowires Processed by Metal Assisted Directional Chemical Etching

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## Objectives

- ◇ To prepared silicon single crystal nanofibers using a silver induced self-catalysis chemical etching process
- ◇ To test the thermoelectric property of the silicon nanofiber

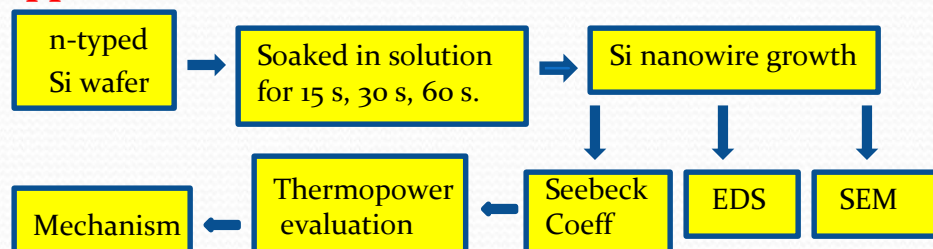
## Background

- ◇ Thermoelectric (TE) materials offer the opportunity for direct conversion of heat into electrical power from temperature differences.
- ◇ Semiconducting materials are often used in TE units because they have high power factors.
- ◇ Silicon has been extensively studied because of the relatively low cost and high figure of merit.
- ◇ Si is compatible with oxide/metallic connecting electrode materials.
- ◇ Nanostructured Si in the form of thin film or nanowire (NW) has higher energy conversion efficiency than bulk silicon.
- ◇ Si NW is often processed by E-beam lithography and chemical vapor deposition (CVD); self-catalysis chemical etching is a new process.

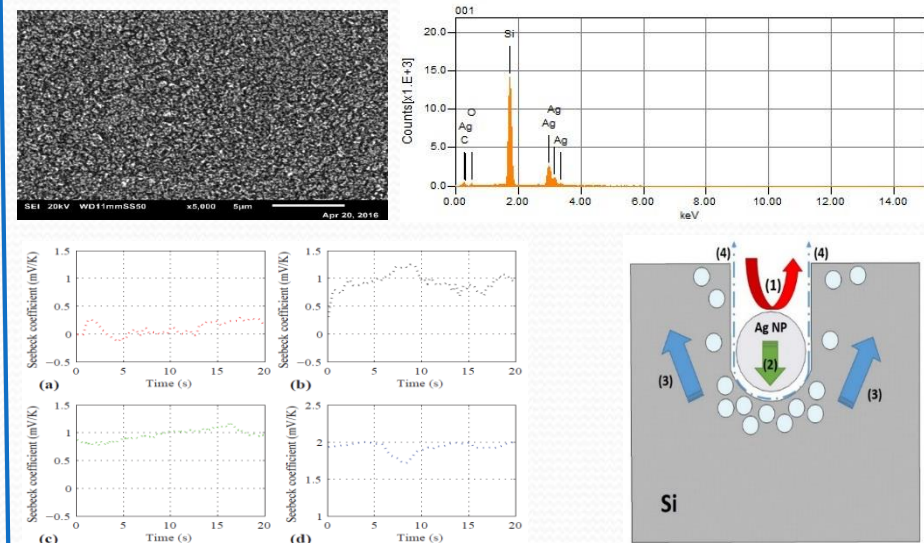
## Materials and Instruments

- ◇ <100> n-type Si wafer pieces with the thickness of 500 micron
- ◇ Solution: 0.01 M AgNO<sub>3</sub>, 0.2 M H<sub>2</sub>O<sub>2</sub> and 4.8 M HF
- ◇ CHI 440C electrochemical workstation for measuring TE property
- ◇ Jeol JSM-6010PLUS/LA SEM with energy dispersive X-ray spectroscopy

## Approaches



## Results and Discussion



## Conclusions

- ◇ SiNWs were successfully synthesized by first depositing Ag NPs onto n-type Si wafer and secondly implementing the MaCE technique.
- ◇ The Seebeck coefficient of the SiNWs is three times higher than that of the original Si wafer.
- ◇ The SiNW with thermoelectric performance improvement is promising for the next generational thermoelectric devices.

## Acknowledgements

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